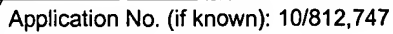



IFW



Certificate of Express Mailing Under 37 CFR 1.10

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


Signature

Signature _____

Donna M. Tirella

Typed or printed name of person signing Certificate

Registration Number, if applicable

212.527.7700
Telephone Number

Note: Each paper must have its own certificate of mailing, or this certificate must identify each submitted paper.

Response to Restriction Requirement (with Traverse) (2 pages)
Return Receipt Postcard



Docket No.: 20110/0200839-US0
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Kazuo Kasai et al.

Application No.: 10/812,747

Confirmation No.: 5489

Filed: March 29, 2004

Art Unit: 1765

For: SILICON SUBSTRATE ETCHING METHOD
AND ETCHING APPARATUS

Examiner: L. Vinh

RESPONSE TO RESTRICTION REQUIREMENT

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the restriction requirement set forth in the Office Action mailed February 27, 2006 (Paper No. 022206), Applicants hereby provisionally elects Group II: Claims 15-24 for continued examination, with traverse.